

jc971 U.S. PTO
09/921456
08/03/01



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Brosnihan et al.

GROUP:

Unknown

SERIAL NO: Unknown

EXAMINER:

Unknown

FILED: Herewith

FOR: BONDED WAFER OPTICAL MEMS PROCESS

Assistant Commissioner of Patents
Washington, D.C. 20231

Sir:

INFORMATION DISCLOSURE STATEMENT

In compliance with 37 C.F.R. §§1.56, 1.97, and 1.98, Applicant submits copies of the documents listed on the attached Form PTO-1449.

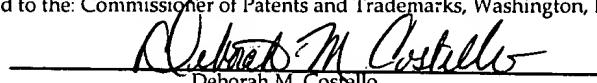
The Commissioner is authorized to charge Deposit Order Account No. 19-0079 for any further fee that is required.

Respectfully submitted,



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I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited on the date shown below in an envelope as "Express Mail Post Office to Addressee" Mailing Label Number EL662368834US addressed to the: Commissioner of Patents and Trademarks, Washington, D.C. 20231.



Deborah M. Costello

Date

8/3/01

FORM PTO-1449 SAMUELS, GAUTHIER & STEVENS LLP (Rev. 5/92) 225 Franklin Street, Boston, MA 02110 Telephone: (617) 426-9180	ATTORNEY DOCKET NO. 5683 <u>Brosnihan et al.</u> APPLICANT <u>Herewith</u> FILING DATE	SERIAL NO. <u>Unknown</u> <u>Unknown</u> GROUP <u>Unknown</u> EXAMINER
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08/03/01

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT****U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	6,121,552	9/19/00	Brosnihan et al.			6/13/97
	AB	6,044,705	4/4/00	Neukermans et al.			5/12/97
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	A1						
	AJ						
	AK						
	AL						
	AM						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER INITIAL		
	AN	"A Raster -Scanning Full-Motion Video Display Using Polysilicon Micromachined Mirrors"; Conant et al., University of California Berkeley & University of California Davis, Engineering II
	AO	"Integrated Micromachined Scanning Display Systems"; by Hagelin et al., Department of Electrical and Computer Engineering; University of Californian Davis & University of California, Berkeley
	AP	"Stretched-Film Micromirrors For Improved Optical Flatness"; by Nee et al.; University of California, Berkeley Sensor & Actuator Center

EXAMINER	DATE CONSIDERED

EXAMINER:	Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
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